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MEMC 98-4650(2293)
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Gregory Michael Wilson et al.
Serial No. 09/608,302
Filed June 30, 2000
Confirmation No. 9819

Art Unit 1765

For A METHOD AND APPARATUS FOR FORMING A SILICON WAFER WITH A
DENUDED ZONE

Examiner Robert M. Kunemund

September 14, 2004

REQUEST FOR EXTENSION OF TIME

Applicants are filing a Continuation application concurrently with the present request, claiming priority to the present application. Accordingly, Applicants submit herewith a check in the amount of \$420.00 to extend the time period for a two(2)-month extension of time to file the Appeal Brief, thereby ensuring that the continuation application is co-pending with the present application. The Commissioner is hereby authorized to charge any under payment or credit any over payment to Deposit Account No. 19-1345.

09/16/2004 SMINASS1 00000015 09608302

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420.00 OP

Respectfully submitted,

Richard A. Schuth, Reg. No. 47,929
SENNIGER, POWERS, LEAVITT & ROEDEL
One Metropolitan Square, 16th Floor
St. Louis, Missouri 63102
(314) 231-5400

RAS/DER/skd